ABSTRACT OF THE DISCLOSURE

LAPPING CONTROL SENSOR FOR MAGNETORESISTIVE EFFECT HEAD, LAPPING CONTROL METHOD USING THE SENSOR AND MANUFACTURING METHOD OF THE SENSOR

A lapping control sensor for a MR head includes a multi-layered structure of a metallic layer, an insulation layer, a resister layer and a lead conductor layer, and being provided in parallel with the MR head which has a multi-layered structure of at least a lower shield layer, a shield gap insulation layer, a MR layer and a lead conductor layer is provided. The insulation layer of the lapping control sensor has a thickness larger than that of the shield gap insulation layer of the MR head. The thickness of the insulation layer of the sensor is 0.1 μm or more.

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